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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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blicant(s):

ZHAN et al.

Group Art Unit: 2877

Serial No.:

09/691.006

Examiner:

Hoa Q. Pham

Filed:

October 18, 2000

Docket No.:

110.01420101

Title:

IMAGING ELLIPSOMETRY

Confirmation No.: 4510

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

We are transmitting the following documents along with this Transmittal Sheet (which is submitted in triplicate):

<u>X</u>	Small entity status is entitled to be asserted in the above-identified application.							
<u>X</u>	An itemized return postcard.							
<u>X</u> <u>X</u> <u>X</u>	documents cited on the 1449 forms.							
		U.S.C. §119.	•					
_	Other: Amendme		No Additional fee is	s required.	The fee has been cal	culated as shown:		
	Fee Calculation for Claims Pending After Amendment							
		Pending Claims after Amendment (1)	Claims Paid for Earlier (2)	Number of Additional Claims (1-2)	Cost per Additional Claim	Additional Fees Required		
Tota	l Claims				x \$9 =			
	Independent Claims x \$43 =							
	One or More New Multiple Dependent Claims Presented? If Yes, Add \$145 Here →							
			Т	otal Additional Cla	nim Fees Required			

Please consider this a PETITION FOR EXTENSION OF TIME for a sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 13-4895. Triplicate copies of this sheet are enclosed.

MUETING, RAASCH & GEBHARDT, P.A.

Customer Number: 26813

Name: Mark J. Gebhardt

Reg. No.: 35,518

Direct Dial: 612-305-1216 Facsimile: 612-305-1228

<u>CERTIFI</u>	ICATE	UNDEF	37	CFR	§1.10	0:
"Evpress						

"Express Mail" mailing label number: EV 405459125 US

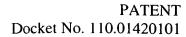
Date of Deposit: March

, 2004

I hereby certify that the Transmittal Letter and the paper(s) and/or fee(s), as described hereinabove, are being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR §1.10 on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

By: Sue Dombroske

(SMALL ENTITY TRANSMITTAL UNDER RULE 1.10)





IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	ZHAN et al.)	Group Art Unit:	2877
Serial No.: Confirmation	09/691,006 No.: 4510)	Examiner:	Hoa Q. Pham
Filed:	October 18, 2000)		
For:	IMAGING ELLIPSOMETRY)		

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

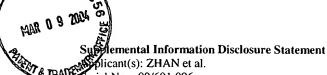
In accordance with the continuing duty of candor and good faith that is to be demonstrated before the United States Patent and Trademark Office (USPTO), enclosed are copies of 18 documents which Applicants bring to the Examiner's attention as possibly being of interest in connection with the above-identified patent application. Per M.P.E.P. §609, the information cited in the present Supplemental Information Disclosure Statement shall not be construed to be an admission that the information is, or is considered to be, material to patentability. Consideration of each of the documents listed on the attached 1449 forms is respectfully requested. Pursuant to the provisions of MPEP §609, Applicants further request that a copy of the 1449 forms, marked as being considered and initialed by the Examiner, be returned with the next Official Communication.

Since this Supplemental Information Disclosure Statement is submitted after receipt of an Office Action in the above-identified patent application, Applicants have included the fee of \$180.00 under 37 CFR §§1.97(c) and 1.17(p). Please charge any additional fees or credit any overpayment to Deposit Account No. 13-4895.

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Serial No.: 09/691,006 Confirmation No.: 4510 Filed: October 18, 2000

For: IMAGING ELLIPSOMETRY

When the Examiner takes up the present application, consideration of these documents is respectfully requested. The Examiner is invited to contact Applicants' Representatives at the below-listed telephone number if they can be of any assistance during prosecution of the present application.

CERTIFICATE UNDER 37 C.F.R. 1.10:

The undersigned hereby certifies that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR §1.10 on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA

22313-1450. Leve Sombroske

By Sue Dombroske

"Express Mail" mailing label number:

March 2004

EV 405459125 US

Date of Deposit: March

. 2004

Date

MJG/skd

Respectfully submitted for

ZHAN et al.

By Mueting, Raasch & Gebhardt, P.A. P.O. Box 581415 Minneapolis, MN 55458-1415 Telephone (612)305-1220 Facsimile (612)305-1228

Attorney: Mark J. Gebhardt

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INFORMATION DISCLOSURE STATEMENT

Atty. Docket No.: 110.0142 0101

Applicant(s): ZHAN et al.

Confirmation No.: 4510

Application Filing Date: 18 October 2000

Group: 2877

Information Disclosure Statement mailed: March 9, 2004

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U.S. PATENT DOCUMENTS

nitial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	4,893,932	01/16/90	Knollenberg			
	5,220,403	06/15/93	Batchelder et al.			
	5,822,073	10/13/98	Yee et al.			
	5,991,488	11/23/99	Salamon et al.			
	6,127,183	10/03/00	Ivarsson et al.			
	6,493,097	12/10/02	Ivarsson			
	6,594,011	07/15/03	Kempen			

FOREIGN PATENT DOCUMENTS

Examiner	Document Number	Date	Country	Class	Subclass	Trans	lation
<u>Initial</u>						Yes	No
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OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial	Document Description				
	Azzam, "Differential reflection phase shift under conditions of attenuated internal reflection," <i>J. Opt. Soc. Am. A</i> , 1999;16(7):1700-1702.				
Bu-Abbud et al., "Characterization of Fabrication Damage in SrTiO ₃ by Int and External Measurements," <i>Surface Science</i> , 1980;96:329-345.					
Burshta et al., "Ellipsometry of guided wave polaritons at solid surfa <i>Science</i> , 1994;301:399-404.					
	Ikeda et al., "Molecular orientation near the surface of a smectic liquid crystal cell showing V-shaped switching by means of attenuated total internal reflection ellipsometry," <i>Physical Review E</i> ; 2001;63:061703-1-7.				
Irene, "Ultra-thin SiO ₂ film studies: index, thickness, roughness ar oxidation regime," Solid State Electronics, 2001;45:1207-1217.					

EXAMINER	Date Considered
*Examiner: Initial if citation considered, whether or not citation is in concompance and not considered. Include copy of this form with next conto	nformance with MPEP 609; Draw line through citation if not in munication to applicant.

INFORMATION DISCLOSURE STATEMENT

Atty. Docket No.: 110.0142 0101 Serial No.: 09/691,006

Applicant(s): ZHAN et al. Confirmation No.: 4510

Application Filing Date: 18 October 2000 Group: 2877

Information Disclosure Statement mailed: March 9, 2004

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Examined Initial	Document Description					
ADTRIBUTE	Johansen et al., "Imaging surface plasmon resonance sensor based on multiple wavelengths: Sensitivity considerations," <i>Review of Scientific Instruments</i> , 2000;71(9):3530-3538.					
	Moy, "Immersion ellipsometry," Applied Optics, 1981;20(22):3821-3822.					
	Pokrowsky, "Optical methods for thickness measurements on thin metal films," <i>Applied Optics</i> , 1991;30(22):3228-3232.					
	Takabayashi et al., "Propagation length of guided waves in lossy Si film sandwiched by identical dielectrics," <i>J. Opt. Soc. Am. B</i> , 1995;12(12):2406-2411.					
	Tiwald et al., "Determination of the mid-IR optical constants of water and lubricants using IR ellipsometry combined with an ATR cell," <i>Thin Solid Films</i> 1998;313-314:718-721.					
	Yablonskii et al., "Control of the bias tilt angles in nematic liquid crystals," <i>J. Appl. Phys.</i> , 1999;85(5):2556-2561.					

EXAMINER	Date Considered

*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.